Test beam 2018: beam composition and purity

V.O.Tikhomirov^{1,2}

¹P.N.Lebedev Physical Institute of the Russian Academy of Sciences and ²National Research Nuclear University "MEPhI"

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e and π in the plots here are samples selected via Preshower and Lead glass cuts as shown on previous slide (left bottom distribution)

Pion sample purity: method1

- 1. Get pion and electron samples using selection in Preshower and Lead Glass
- 2. Look on Cherenkov signal of pion sample,
- 3. Calculate fraction of events in this distribution with signal above electron threshold (230 channel of QDC). This is first approximation to estimate electron contamination in the pion sample (= 0.017).
- 4. Apply correction: due to not 100% efficiency of Cherenkov some part of electrons may have a signal below 230 QDC threshold, so are situated in this region. To estimate this efficiency of Cherenkov counter look on electron sample and calculate fraction of events above 230 threshold (= 0.84).
- 5. Final estimation of pion sample impurity (i.e. fraction of electrons in pion sample): 0.017/0.84 = 0.02



Pion sample purity: method1

• Remark: if exclude this region from definition of pion sample, the pion sample impurity will be 0.004, i.e. 5 times smaller. Muons? Double particles in event?

Lead glass calorimeter vs Cherenkov/counter





• Contamination of pions in selected electrons can be estimated via number of events in this excess. Rough estimation gives 0.005 of electron sample impurity, i.e. fraction of pions in elrectron sample.

• More accurate estimation can be obtained via fit - trying





Result: obtained pion contamination in selected electron sample = 0.0069

Remark: Both electron sample definition and pion contamination fraction are cut-dependent.

